

Electronic Patent Application Fee Transmittal

Application Number:	10689617
Filing Date:	22-Oct-2003
Title of Invention:	Method for cleaning plasma etching apparatus, method for plasma etching, and method for manufacturing semiconductor device
First Named Inventor/Applicant Name:	Satoru Okamoto
Filer:	Diana DiBerardino/Arlene Yates
Attorney Docket Number:	12732-170001

Filed as Large Entity

Utility under 35 USC 111(a) Filing Fees

Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
-------------	----------	----------	--------	----------------------

Basic Filing:

Pages:

Claims:

Miscellaneous-Filing:

Petition:

Patent-Appeals-and-Interference:

Filing a brief in support of an appeal	1402	1	540	540
--	------	---	-----	-----

Post-Allowance-and-Post-Issuance:

Extension-of-Time:

Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Extension - 1 month with \$0 paid	1251	1	130	130
Miscellaneous:				
Total in USD (\$)				670